

U.S. DEPARTMENT OF COMMERCE

PATENT AND TRADEMARK OFFICE

LIST OF REFERENCES CITED BY APPLICANT(S)

(Use several sheets if necessary)

ATTY DOCKET NO.

862.C2173

APPLICATION NO.

09/819,906

APPLICANT

Yasuhiro SHIMADA, et al.

FILING DATE

March 29, 2001

GROUP

2881

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
KN	5,834,783	11/10/1998	Muraki, et al.	250	398	
	5,864,142	01/26/1999	Muraki, et al.	250	491.1	
	5,905,267	05/18/1999	Muraki	250	492.22	
	5,981,954	11/09/1999	Muraki	250	397	
	6,107,636	08/22/2000	Muraki	250	492.2	
	6,104,035	08/15/2000	Muraki	250	492.22	
	6,166,387	12/26/2000	Muraki, et al.	250	492.2	
	5,929,454	07/27/1999	Muraki, et al.	250	491.1	
	5,939,725	08/17/1999	Muraki	250	492.22	
	5,973,332	10/26/1999	Muraki, et al.	250	492.2	
	6,137,113	10/24/2000	Muraki	250	492.22	
KN	4,419,580	12/06/1983	Walker, et al.	250	396 R	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

K. MUYEN

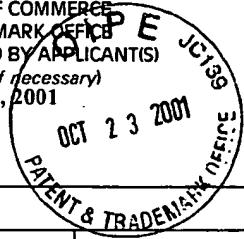
DATE CONSIDERED

03-01-03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.

Sheet 1 of 2

ATTY DOCKET NO.
862.C2173APPLICATION NO.
09/819,906APPLICANT
Yasuhir SHIMADA, et al.FILING DATE
March 29, 2001GROUP
2881

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

lnr	“Sub-Nanometer Miniature Electron Microscope”, A.D. Feinerman, et al., Journal of Vacuum Science and Technology A, Vol. 10, No. 4, July/August 1992, 611-616.
1	“High Aspect Ratio Aligned Multilayer Microstructure Fabrication”, K. Y. Lee, et al., Journal of Vacuum Science and Technology B, Vol. 12, No. 6, November/December 1994, pp. 3425-3430.
	“Arrayed Miniature Electron Beam Columns For High Throughput Sub-100 nm Lithography”, T. H. P. Chang, et al., Journal of Vacuum Science and Technology B, Vol. 10, No. 6, November/December 1992, pp. 2743-2748.
	“Microstructures for Particle Beam Control”, G. W. Jones, et al., Journal of Vacuum Science and Technology B, Vol. 6, No. 6, November/December 1988, pp. 2023-2027.
lnr	“A Multibeam Scheme for Electron-Beam Lithography”, T. Sasaki, Journal of Vacuum Science and Technology, Vol. 19, No. 4, November/December 1981, pp. 963-965.

EXAMINER

L. MAYER

DATE CONSIDERED

03-01-03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.

SEW/lmj

Sheet 2 of 2